



FRT MicroProf FE – Tool Overview

	FRT MicroProf 300 FE
Cleanroom / Minienvironment	<ul style="list-style-type: none"> ▪ EFEM Housing (ISO 3 compatible), ISO 3 Minienvironment (FFUs)
SMIF	<ul style="list-style-type: none"> ▪ 2x Brooks Versaport 2200 Loadports (Fortrend not supported) ▪ SEMI E84 compatible
Wafer Handling	<ul style="list-style-type: none"> ▪ GaAs, Si, Sapphire with +/- 200 µm Bow and 4 mm Thickness ▪ Different Wafer cassettes (13 / 25 slot) possible ▪ Prealigner, OCR Reader
Sensors	<ul style="list-style-type: none"> ▪ CWL 3 mm (Wafer Bow, Wafer Thickness) ▪ WLI / CFM DT (Chip Topography) ▪ IRT 80 (Film Thickness) ▪ FTR UV-VIS-NIR (Thin Film Thickness)
MTBF / MTBA / MTTR / Uptime	<ul style="list-style-type: none"> ▪ > 500 h / 50 h / 4 h / > 95 %
Service	<ul style="list-style-type: none"> ▪
Lead Time	<ul style="list-style-type: none"> ▪
Warranty	<ul style="list-style-type: none"> ▪